coolant, and (iii) a second heat exchanger for exchanging heat between air supplied into the chamber and the coolant. The refrigerant is circulated between the refrigerator and the first heat exchanger, and the coolant is circulated between the first and second heat exchangers.

IN THE CLAIMS:

Please cancel Claim 10 without prejudice or disclaimer of the subject matter recited therein.

Please amend Claims 1, 7, 8, 9 and 11 as follows. A marked-up copy of the amended claims showing the changes made thereto, is attached. Note that all the claims currently pending in this application, including those not presently being amended, have been reproduced below for the Examiner's convenience.

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(Amended) An apparatus, comprising:

a chamber enclosing semiconductor manufacturing equipment; and an air conditioner for controlling air which is supplied into said chamber, said air conditioner including (i) a refrigerator using a refrigerant, (ii) a first heat exchanger for exchanging heat between the refrigerant and a coolant, and (iii) a second heat exchanger for exchanging heat between the coolant and the air which is supplied into said chamber, wherein

the refrigerant is circulated between said refrigerator and said first heat exchanger, and said coolant is circulated between said first and second heat exchangers.

- 2. (Unamended) An apparatus according to Claim 1, wherein said air conditioner further includes an air blower.
- 3. (Unamended) An apparatus according to Claim 1, wherein said air conditioner further includes a heater.
- 4. (Unamended) An apparatus according to Claim 1, wherein said first heater exchanger comprises an evaporator.
- 5. (Unamended) An apparatus according to Claim 1, wherein said refrigerator comprises a compressor and a condenser.
- 6. (Unamended) An apparatus according to Claim 1, further comprising a reservoir and a pump provided between said first and second heat exchangers.
- 7. (Amended) An apparatus according to Claim 1, wherein at least a portion of said air conditioner is disposed adjacent said chamber.
- 8. (Amended) An apparatus according to Claim 7, wherein said second heat exchanger is disposed adjacent said chamber, and wherein said refrigerator and said first heat exchanger are disposed separately from said chamber.

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equipment selected from the group consisting of an inspection equipment and a measuring equipment, disposed inside said chamber.

Please add new Claims 18-20 as follows:

- 18. (New) An apparatus according to Claim 1, wherein the semiconductor manufacturing equipment is a semiconductor exposure apparatus.
- 19. (New) An apparatus according to Claim 11, wherein the inspection equipment is a mask inspection equipment.
- 20. (New) An apparatus according to Claim 11, wherein the measuring equipment is a laser interferometer.

REMARKS

Claims 1-9, 11 and 18-20 are presented for consideration, with Claim 1 being independent.

The specification and abstract have been reviewed and amended to correct minor informalities and improve their idiomatic English form. In addition, independent Claim 1 and selected dependent claims have been amended to more clearly distinguish Applicants'